	Application No.	Applicant(s)	
Notice of Allowability	10/565,373	KIM, HO SEOB	
	Examiner	Art Unit	
	Bernard E. Souw	2881	
The MAILING DATE of this communication ap All claims being allowable, PROSECUTION ON THE MERITS herewith (or previously mailed), a Notice of Allowance (PTOL-8 NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT of the Office or upon petition by the applicant. See 37 CFR 1.3	IS (OR REMAINS) CLOSED in 35) or other appropriate communication. This application is s	this application. If not included inication will be mailed in due course. TH	IS iative
1. X This communication is responsive to 1/20/2006 (Pre Am	nendment).		
2. X The allowed claim(s) is/are 1-20.			
 3.		or (f).	
Certified copies of the priority documents have 2. Certified copies of the priority documents have		n No	
3. Copies of the certified copies of the priority			е
International Bureau (PCT Rule 17.2(a)).	accuments have been received	The state of the s	
* Certified copies not received:			
Applicant has THREE MONTHS FROM THE "MAILING DAT noted below. Failure to timely comply will result in ABANDOI THIS THREE-MONTH PERIOD IS NOT EXTENDABLE. 4. A SUBSTITUTE OATH OR DECLARATION must be sul INFORMAL PATENT APPLICATION (PTO-152) which go to the complete of th	NMENT of this application. bmitted. Note the attached EXA gives reason(s) why the oath or nust be submitted. erson's Patent Drawing Review	MINER'S AMENDMENT or NOTICE OF declaration is deficient.	
1) hereto or 2) to Paper No./Mail Date			
(b) ☐ including changes required by the attached Examin Paper No./Mail Date			
Identifying indicia such as the application number (see 37 CFI each sheet. Replacement sheet(s) should be labeled as such i	R 1.84(c)) should be written on t in the header according to 37 CF	ne drawings In the front (not the back) of R 1.121(d).	
6. DEPOSIT OF and/or INFORMATION about the de attached Examiner's comment regarding REQUIREMEN	POSIT OF BIOLOGICAL MATE NT FOR THE DEPOSIT OF BIO	ERIAL must be submitted. Note the DLOGICAL MATERIAL.	
Attachment(s) 1. ☑ Notice of References Cited (PTO-892)	-	formal Patent Application	
2. Notice of Draftperson's Patent Drawing Review (PTO-94)		ummary (PTO-413), Mail Date	
Information Disclosure Statements (PTO/SB/08), Paper No./Mail Date	7. Examiner's	Amendment/Comment	
Examiner's Comment Regarding Requirement for Deposition of Biological Material	it 8. ⊠ Examiner's	Statement of Reasons for Allowance	
or biological maiorial	9.		

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DETAILED ACTION

Priority

1: Receipt is acknowledged of papers submitted under 35 U.S.C. 119(a)-(d), (JP-

10-2003-0051474), filed 07/25/2003, which papers have been placed of record in the

file.

2. Receipt is acknowledged of papers submitted under 35 U.S.C. 371

(PCT/KR2004/001841) which papers have been placed of record in the file.

Information Disclosure Statement

3. The references cited in the Search Report to PCT/KR2004/001841 filed on

01/20/2006 have been considered, but will not be listed on any patent resulting from this

application because they were not provided on a separate list in compliance with 37

CFR 1.98(a)(1). In order to have the references printed on such resulting patent, a

separate listing, preferably on a PTO/SB08A and 08B form, must be filed within ONE

MONTH of the mailing date of this communication. NO EXTENSION OF TIME WILL

BE GRANTED UNDER EITHER 37 CFR 1.136(a) OR (b) to comply with this

requirement.

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Preliminary Amendment

4. The Preliminary Amendment filed on 01/20/2006 has been entered. The present Office Action is made with all the suggested amendments being fully considered.

The claims have been amended.

No claim has been cancelled.

New claims 9-20 have been added.

Claims 1-20 are pending in this Office Action.

ALLOWANCE

5. Claims 1-20 are allowed.

Reasons for Allowance

- 6. The following is an examiner's statement of reasons for allowance:
- Claim 1 is allowed for reciting a method for manufacturing a lens assembly of an electron beam microcolumn having a plurality of microlenses, each provided with a hole at a central position thereof, and a plurality of insulating layers alternately interposed between the microlenses, the method comprising:
- forming at least one first microlens assembly by anodic-bonding an insulating layer and a microlens together, so that a part of a surface of the insulating layer is not covered by the microlens;
- layering the first microlens assembly on a second microlens or a second microlens assembly, while aligning the holes of the microlenses, so that the second microlens

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or the microlens of the second microlens assembly is in contact with the insulating layer

of the first microlens assembly, while the part of the insulating layer of the first microlens

assembly that is not covered by the first microlens is in contact with the second

microlens or the microlens of the second microlens assembly; and

- scanning a laser beam to bond the part of the insulating layer of the first microlens

assembly that is not covered by the first microlens to the second microlens or the

microlens of the second microlens assembly by passing the laser beam through the part

of the insulating layer of the first microlens assembly, thus welding the first microlens

assembly to the second microlens or the microlens of the second microlens assembly.

Claim 2 is additionally allowed for reciting the same method as claim 1, with an

additional step that the microlens and the insulating layer of each of the microlens

assembly are anodic-bonded together after the microlens of each of the microlens

assembly is rotated on the insulating layer around the hole thereof at a predetermined

angle.

► Claims 8 and 15 are also allowed for reciting a lens assembly manufactured

through the method of claims 1 and 2, respectively.

Claims 3-7, 9-14, and 16-20 are also allowed for their dependency, either directly

or indirectly, to the previously allowed claim 1, 2, 8 or 15.

Relevant Prior Art

7. This prior art made of record and not relied upon is considered pertinent to

applicant's disclosure:

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(a) USPAT 6,281,508 issued to Lee et al. discloses a method for manufacturing a lens assembly for an electron beam microcolumn having a plurality of microlenses and a plurality of insulating layers alternately interposed between the microlenses, each microlens layer and insulating layer having an alignment hole. However, unlike the present invention, Lee's alignment hole does not need to be at a central position, as can be seen in Figs.1 and 5. This is because, as recited by Lee et al. in Col.5/II.8-11, laser welding is only an alternative to anodic bonding to attach the stack to each other, so there is no necessity to align the insulating layer and the microlens in such a way that a part of a surface of the insulating layer is not covered with the microlens. The latter is

(b) USPAT 6,195,214 issued to Muray et al. discloses a method for manufacturing a lens assembly for an electron beam microcolumn having a plurality of microlenses and a plurality of insulating layers alternately interposed between the microlenses, which are bonded together by means of laser spot welding instead of anodic bonding. Therefore, Muray's insulating layer must be aligned to the microlens in such a way that a part of a surface of the insulating layer is not covered with the microlens, i.e., for the laser beam to pass through and carry out the spot welding. However, Muray's invention does not make use of alignment hole.

required by the present invention, since laser-welding is part of the claim limitations.

Communications

8. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Bernard E Souw, Ph.D., whose telephone number is

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571 272 2482. The examiner can normally be reached on Monday thru Friday, 9:00 am to 5:00 pm...

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor. Robert Kim can be reached on 571 272 2293. The central fax phone number for the organization where this application or proceeding is assigned is 571 273 8300 for regular communications as well as for After Final communications.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 571 272 5993.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic David A. Vonove Princy Franker Art Unit 2501 Business Center (EBC) at 866-217-9197 (toll-free).

bes July 28, 2007